

Central European Institute of Technology BRNO | CZECH REPUBLIC



[Instrument contacts updated 22 Oct 2019]

Spring Ceitec Nano
User Meeting 19

CF Nano User Committee usercom@ceitec.vutbr.cz



Contents

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Members of the Committee



Michal Staňo

- Chairman of the Committee
- Junior researcher
- Nanomagnetism and spintronics

CF Nano User Committee usercom@ceitec.vutbr.cz



Lukáš Flajšman

- Member of the Committee
- Ph.D. student
- Fabrication and Characterisation of Nanostructures



David Salamon

- Member of the Committee
- Senior researcher
- Advanced Ceramic Materials



Eva Šťastná

- Member of the Committee
- Ph.D. student
- Advanced Ceramic Materials



Igor Turčan

- Member of the Committee
- Ph.D. student
- Fabrication and Characterisation of Nanostructures





Activities of the Committeee

- Meetings with Head of CEITEC Nano every 3 months
- Presence at CEITEC Nano regular meetings (weekly)
- Improvement of work environment in CF labs
- Communication between users and User office, core facility specialists (operators) etc.







Feedback system

• USE IT! USE IT! Thank you.







+ additional comments (what you liked, what made you angry, what didn't work...)

- The fastest communication channel between you and CF User office, operators...
- Your comments are checked every day → fast problem solution
- Give your feedback: http://cfnano.ceitec.cz/feedback/
- Statistics: http://cfnano.ceitec.cz/feedback/report





Cleanness of the Cleanrooms

- Do not bring incompatible materials inside
- Clean your work area when finished
- Set a good example
- Let's keep it clean!







Booking culture

- You have to cancel your reservation in the last minute?
 WRITE AN EMAIL to all the users.
- You finish your work much earlier?
 WRITE AN EMAIL to the user who has reservation after you.
- Don't make too many reservations of the one machine ahead
 Only two future reservations per instrument withing standard working hours (Mo-Fri, 8am-5pm)
- Don't book the machine for the whole day (if it is not really necessary).
- http://nano.ceitec.cz/rules-for-equipment-reservations/





New instruments



- Magnetometry and transport measurements (VersaLab)
- Confocal Raman imaging system (WITec alpha300 R)
- Critical Point Dryer (Tousimis Autosamdri-815B)
- High vacuum AFM (NanoScan VLS-80)
- New investments (=instruments) after 2020
- New software modules for Lyra FIM-SEM microscope
 - Image snapper (automatic large area imaging)
 - Sample observer for making videos
 - contact: Tomáš Šamořil tomas.samoril@ceitec.vutbr.cz









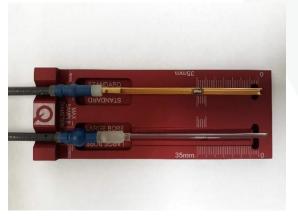




VersaLab [New instruments]

- Magnetometry and transport measurement
- Temperature 50-400K (400-1000K oven kit)
- Magnetic field up to 3T
- Sample size <7mm (<4mm standard coils)
- Sensitivity < 1 µemu (magnetometry), 1nV @ 100mA (ETO)
- Jon Ander Arregi Uribeetxebarria: ja.arregi@ceitec.vutbr.cz





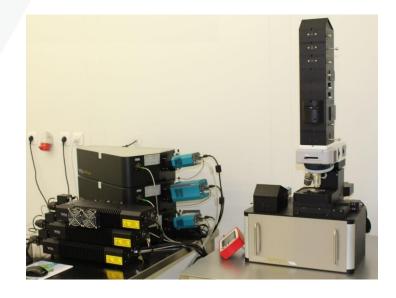






WITec alpha300 R [New instruments]

- Confocal Raman imaging system
- Info on chemical composition and molecular structure
- Raman spectrum at every image pixel with a resolution down to the optical diffraction limit
- Martin konečný: martin.konecny@ceitec.vutbr.cz









Critical Point Dryer [New instruments]

- Wafer and MEMS drying (photolithography lab C100)
- Jiří Zita: jiri.zita@ceitec.vutbr.cz



Critical Point Dryer (CPD)

now available in the booking system

- Well established method for wafer and MEMS drying
- It reduces the effects of deformation and shrinkage that occur when drying samples by conventional evaporation
- Available for:
 - 5x 4" wafer
 - 5x 3" wafer
 - 5x 2" wafer
 - Sample basket for 1 cm² samples
- Contact Jiří Zita to get the certificate

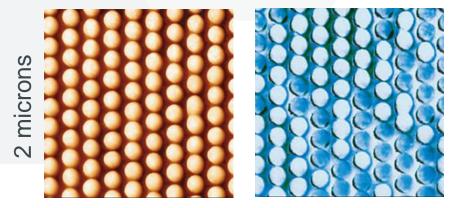




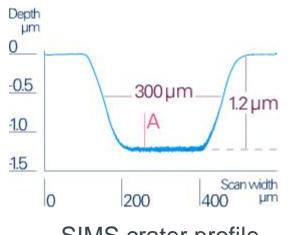
NanoScan VLS-80 [New instruments]



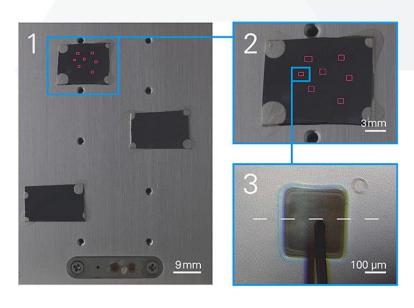
- High vacuum (<5e-6mbar) Atomic Force Microscope (AFM)
- Vacuum = Higher sensitivity, but more difficult to operate
- Multifrequency, Double-Pass, hr-MFM, KPFM, Long-distance Profiling
- Compatible with IONTOF SIMS holders crater measurements
- Magnetic force microscopy: in-plane (200mT) or out-of-plane field (550mT)
- Michal Staňo: michal.stano@ceitec.vutbr.cz



Dual -PLL: 1pass AFM (left) + MFM (rigth)



SIMS crater profile







Communication channels



Facebook group: Ceitec Nano research infrastructure, @ceitecnano



WhatsApp: CEITEC Nano Users



Email: <u>usercom@ceitec.vutbr.cz</u>



Personal contact





Thank you for your attention!

CF Nano User Committee usercom@ceitec.vutbr.cz

http://nano.ceitec.cz/user-committee/ nano.ceitec.cz > User Access and services > User Committee



